03500.015382

## **PATENT APPLICATION**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

TAKAHARU KONDO ET AL

Application No.: 09/866/665

Filed: May 30, 2001

For: SILICON-TYPE THIN FILM
FORMATION PROCESS, SILICONTYPE THIN FILM, AND
PHOTOVOLTAIC DEVICE

February 26, 2003

Commissioner for Patents BOX AF Washington, D.C. 20231

## RESPONSE TO OFFICE ACTION AND REQUEST FOR RECONSIDERATION

Sir:

In response to the Office Action dated November 26, 2002, the Examiner is respectfully requested to consider to following:

I hereby certify that this correspondence is being facsimile transmitted to the United States Patent and Trademark Office (Fax No. 703-372-9311) on

February 26, 2003
(Date of Transmission)

Lock See Yu-Jahnes (Reg. No. 38,667)
(Name of Attorney for Applicants)

Pebniary 26, 2003 (Date of Signature)